



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

ONO, Toshiaki et al.

Group Art Unit: 1765

Serial No.: **09/883,922**

Examiner: **ANDERSON, M.**

Filed: **June 20, 2001**

P.T.O. Confirmation No.: **3735**

For: **METHOD OF MANUFACTURING EPITAXIAL WAFER AND METHOD OF PRODUCING SINGLE CRYSTAL AS MATERIAL THEREFOR**

AMENDMENT UNDER 37 CFR §1.111

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

June 20, 2003

Sir:

In response to the Office Action dated February 26, 2003, please amend the above-identified application as follows:

#71A
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1/2/03
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JUN 25 2003
TC 1700